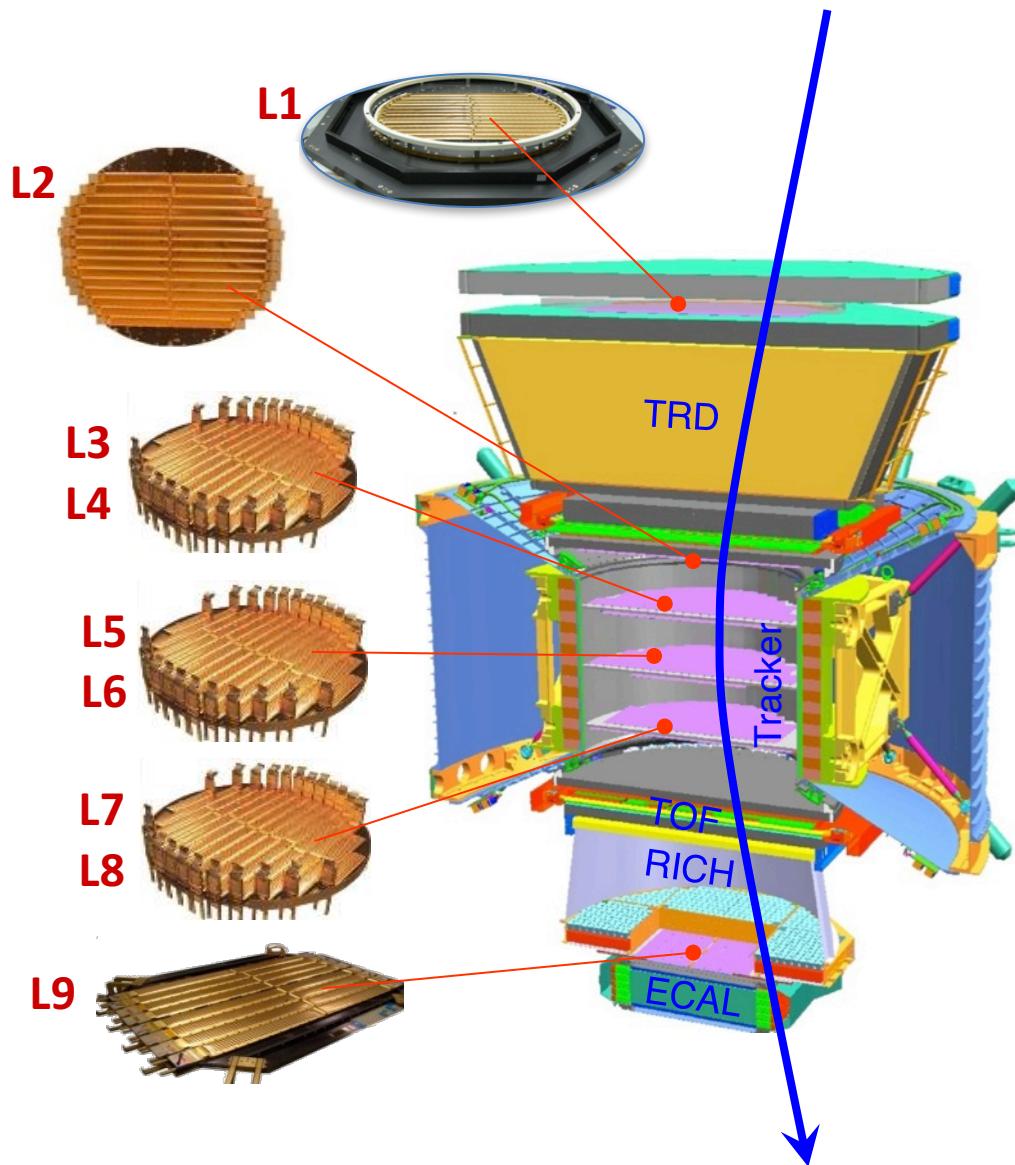


Strip Silicon Charge Detector Performance

A. Oliva

Istituto Nazionale di Fisica Nucleare, Sezione di Bologna

AMS-02 Silicon Tracker



9 layers of **300 μm** thickness **double-sided** silicon sensors arranged in 192 ladders.

6 honeycomb carbon fiber planes. Overall detector material of about $0.04 X_0$.

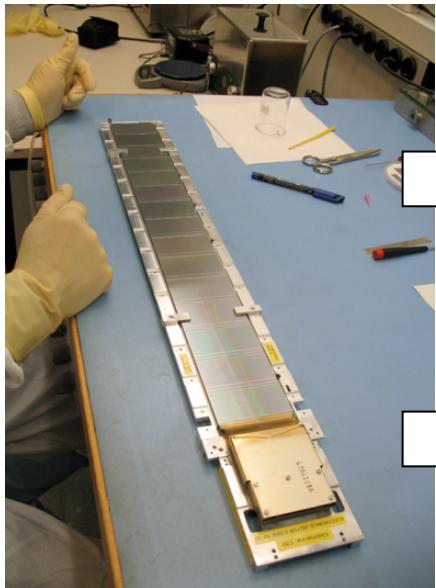
A total of **196k channels**.

About **10 μm** for $Z=1$ and **5 μm** for $Z>1$ bending coordinate spatial resolution.

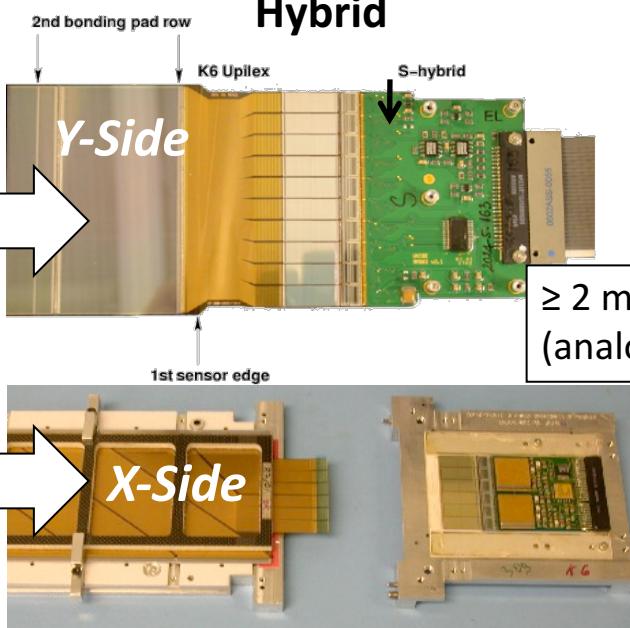
High dynamic range front end for charge measurement (Z measurement up to Iron).

AMS-02 Silicon Tracker Readout

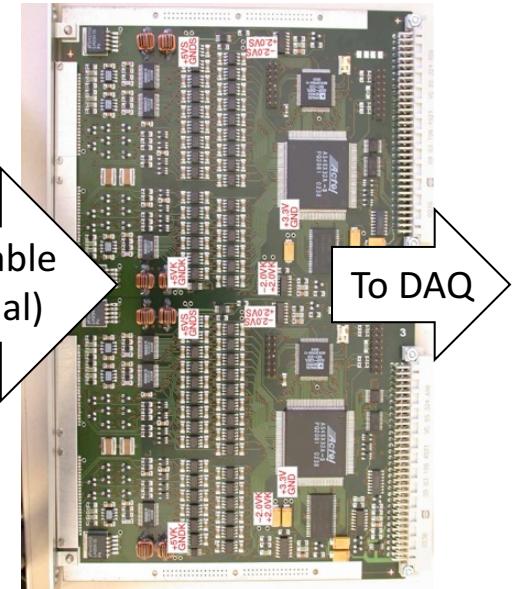
Sensor



Hybrid



Data Reduction



$300\text{ }\mu\text{m}$, $7 \times 4\text{ cm}^2$

$27.5(104)\text{ }\mu\text{m}$ strip impl. pitch

$110(208)\text{ }\mu\text{m}$ readout pitch

Charge sharing

Capacitive coupling (1 pF/cm)

$640(384)$ readout channels

Amplification (100 MIP range)

Shaping ($4\text{ }\mu\text{s}$)

Sample-and-Hold

Each channel 0.7 mW power

$10(6)\text{ VA_hdr64a}$

3 ADC

Pedestal/Noise eval.

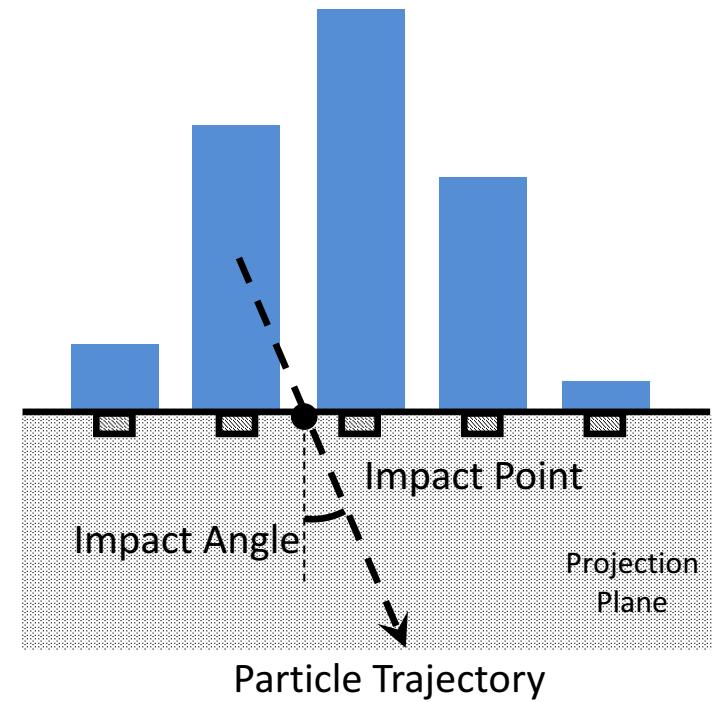
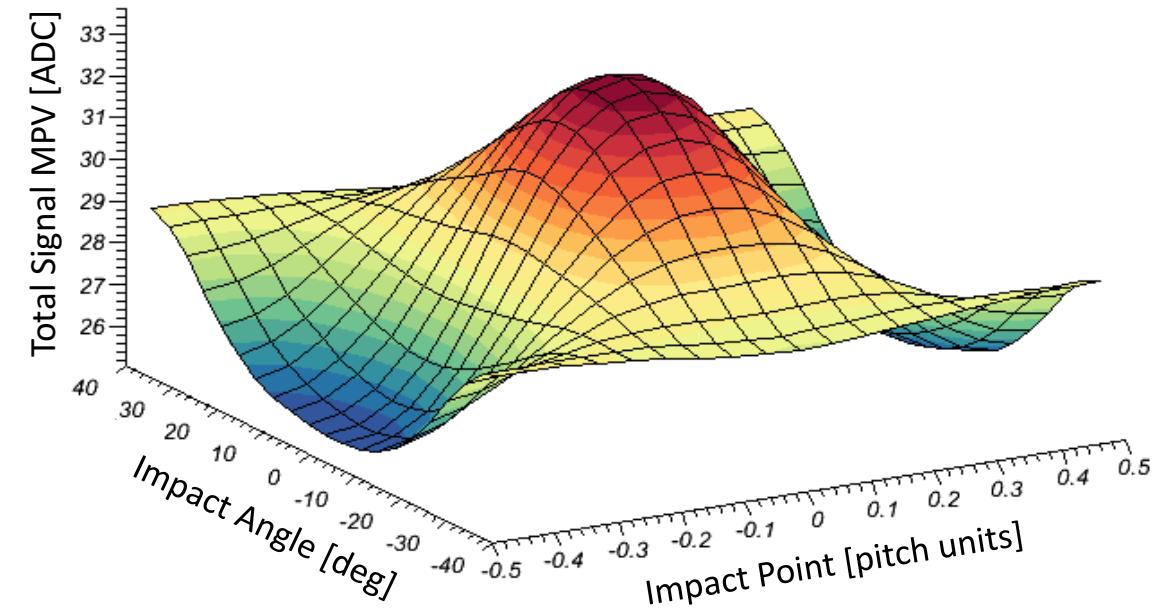
Common noise sub.

Cluster search

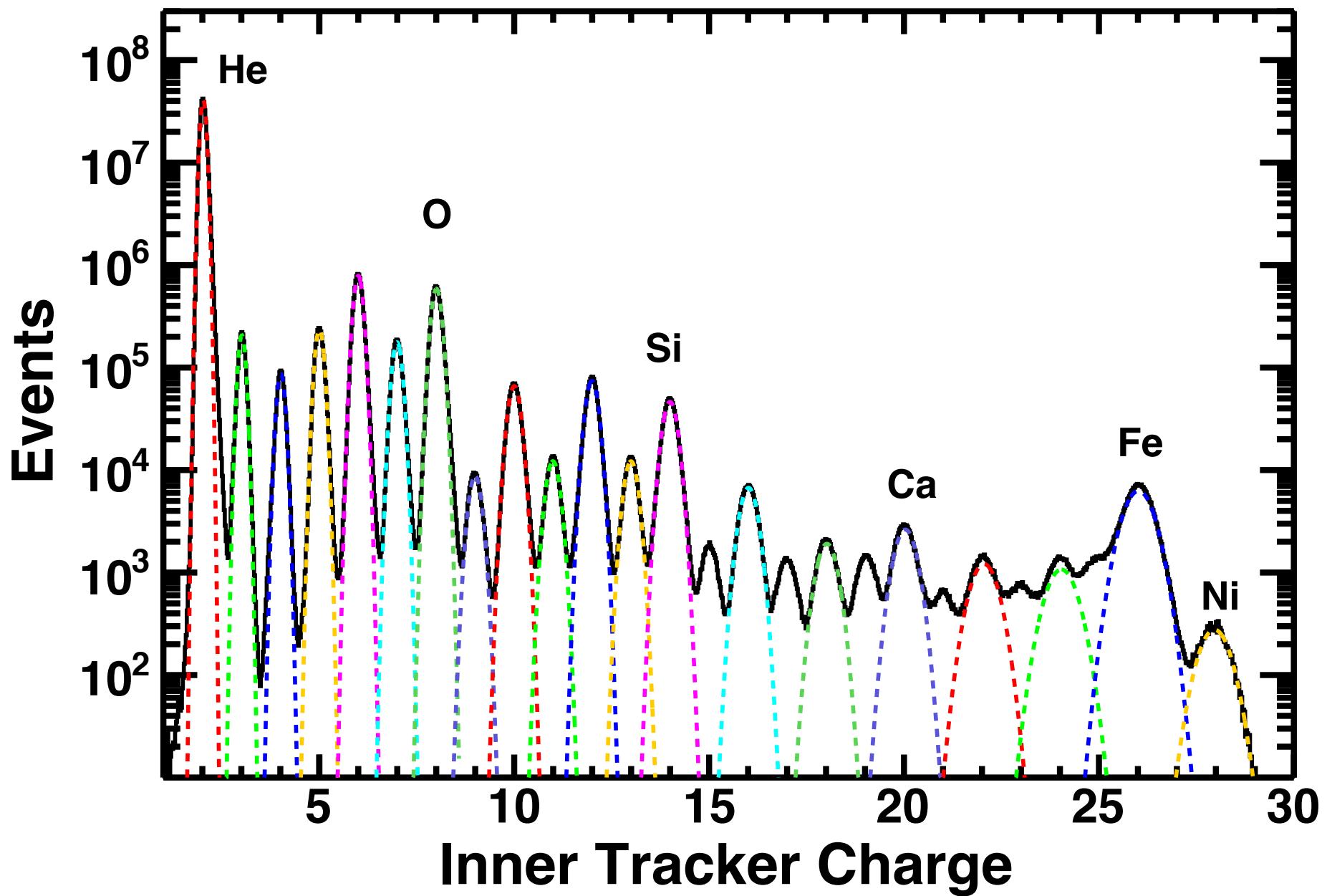
Comp. factor of ~ 1000

AMS-02 Tracker Charge Calibration

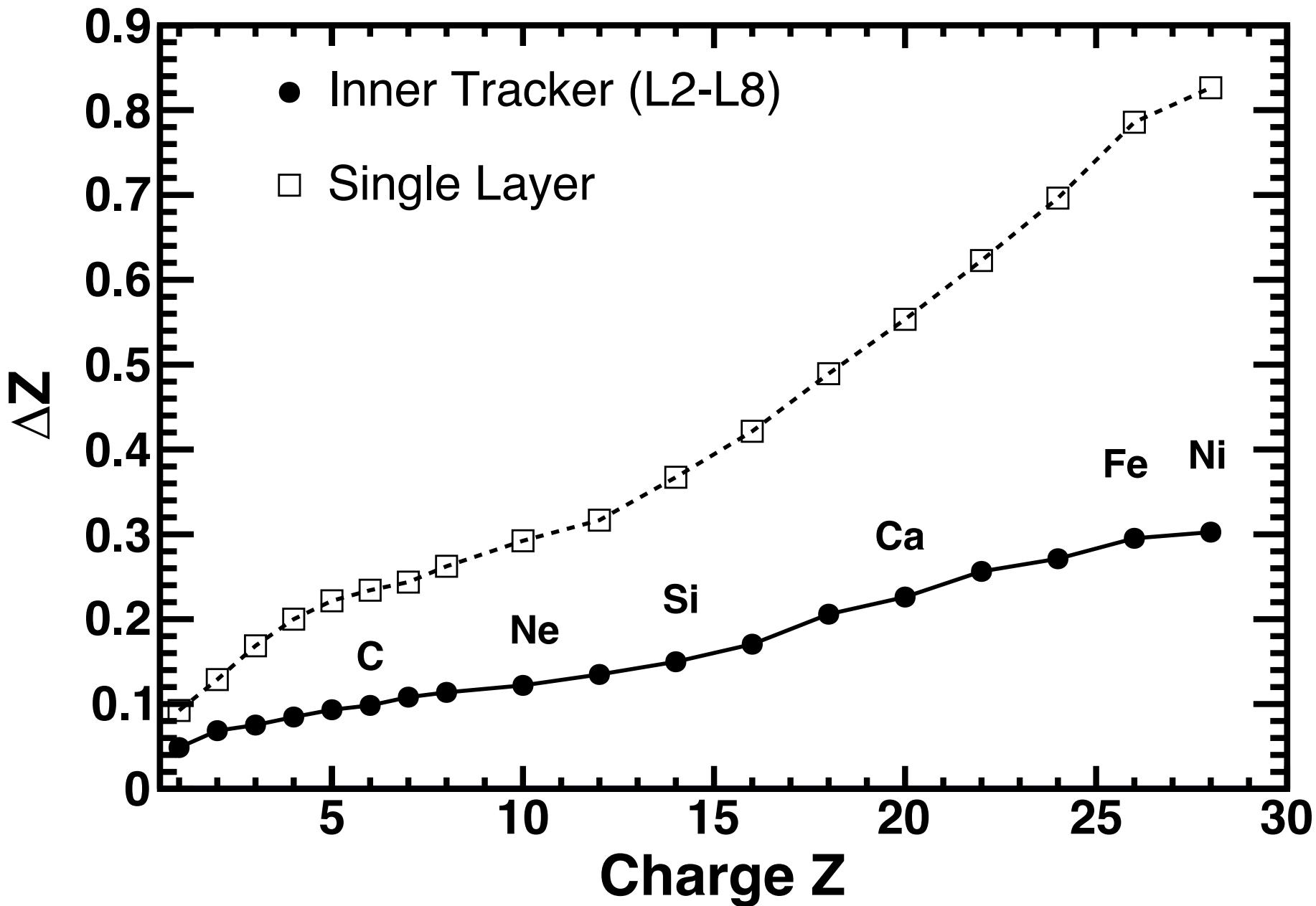
Use of the first highest 5 strips of the cluster separately.
Equalization of 3072 VAs as function of charge (non-linearities).
Path-length correction.
Correction of charge collection effects (coordinate and angular dependences).
Description of the dependence with energy ($\sim 1/\beta^2$).
Time variation correction.



AMS-02 Inner Tracker Charge (L2-L8)

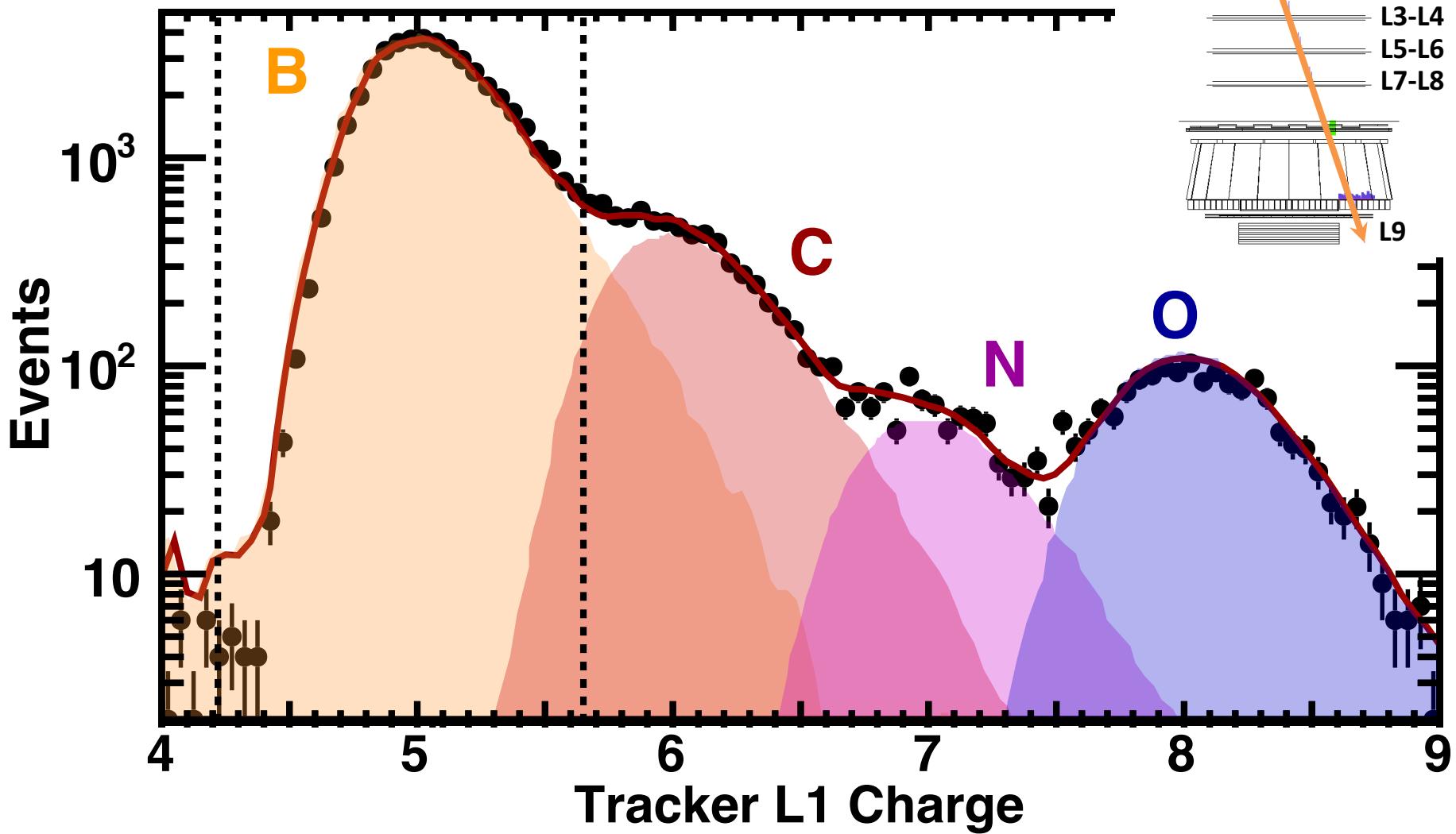


AMS-02 Tracker Charge Resolution



The Importance of Measuring Charge at the Top-of-the-Instrument

L1 is used for *background estimation* (interaction inside AMS),
and for *MC interaction tuning* (selecting samples of incident nuclei).



Energy Loss (from Particle Data Book)

$$k = \frac{\xi}{W_{\max}}$$

Vavilov parameter

$$\xi = \frac{K}{2} \frac{Z}{A} \frac{z^2}{\beta^2} \rho x$$

$$\xi [\text{MeV}] = 0.1535 \frac{K}{2} \frac{Z}{A} \frac{z^2}{\beta^2} X [\text{g/cm}^2]$$

Landau width

$$W_{\max} = \frac{2m_e c^2 \beta^2 \gamma^2}{1 + 2\gamma \frac{m_e}{M} + \left(\frac{m_e}{M}\right)^2} \stackrel{m_e \gamma \ll M}{=} 2m_e c^2 \beta^2 \gamma^2$$

Maximum energy transfer to e⁻

For Silicon below 1 mm Silicon, $\beta \approx 1$, and impinging nuclei,
k is below 0.1, corresponding to **Landau regime**.

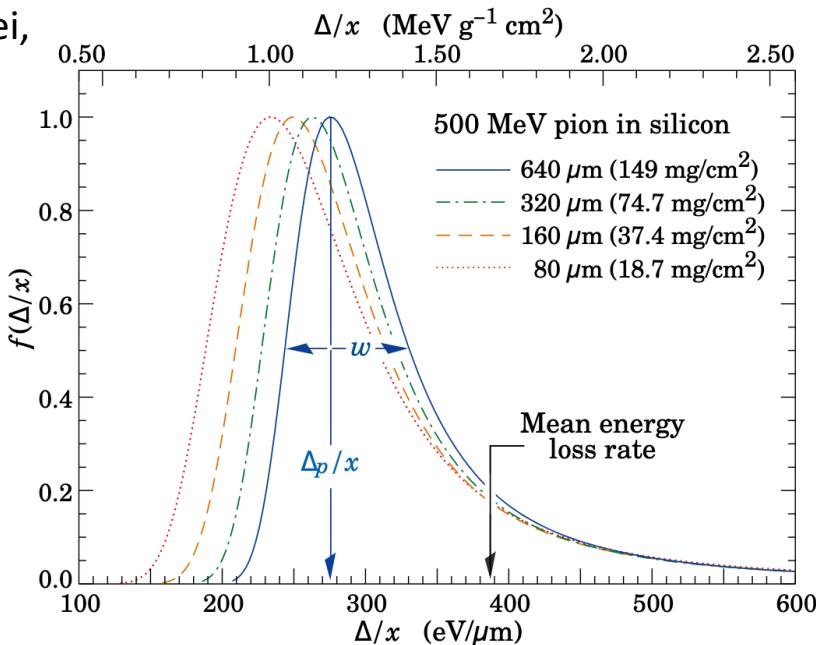
Landau most probable energy loss:

$$\Delta_p = \xi \left[\ln \frac{2m_e c^2 \beta^2 \gamma^2}{I} + \ln \frac{\xi}{I} + 0.2 - \beta^2 - \delta(\beta\gamma) \right]$$

Landau full-width at half maximum (FWHM):

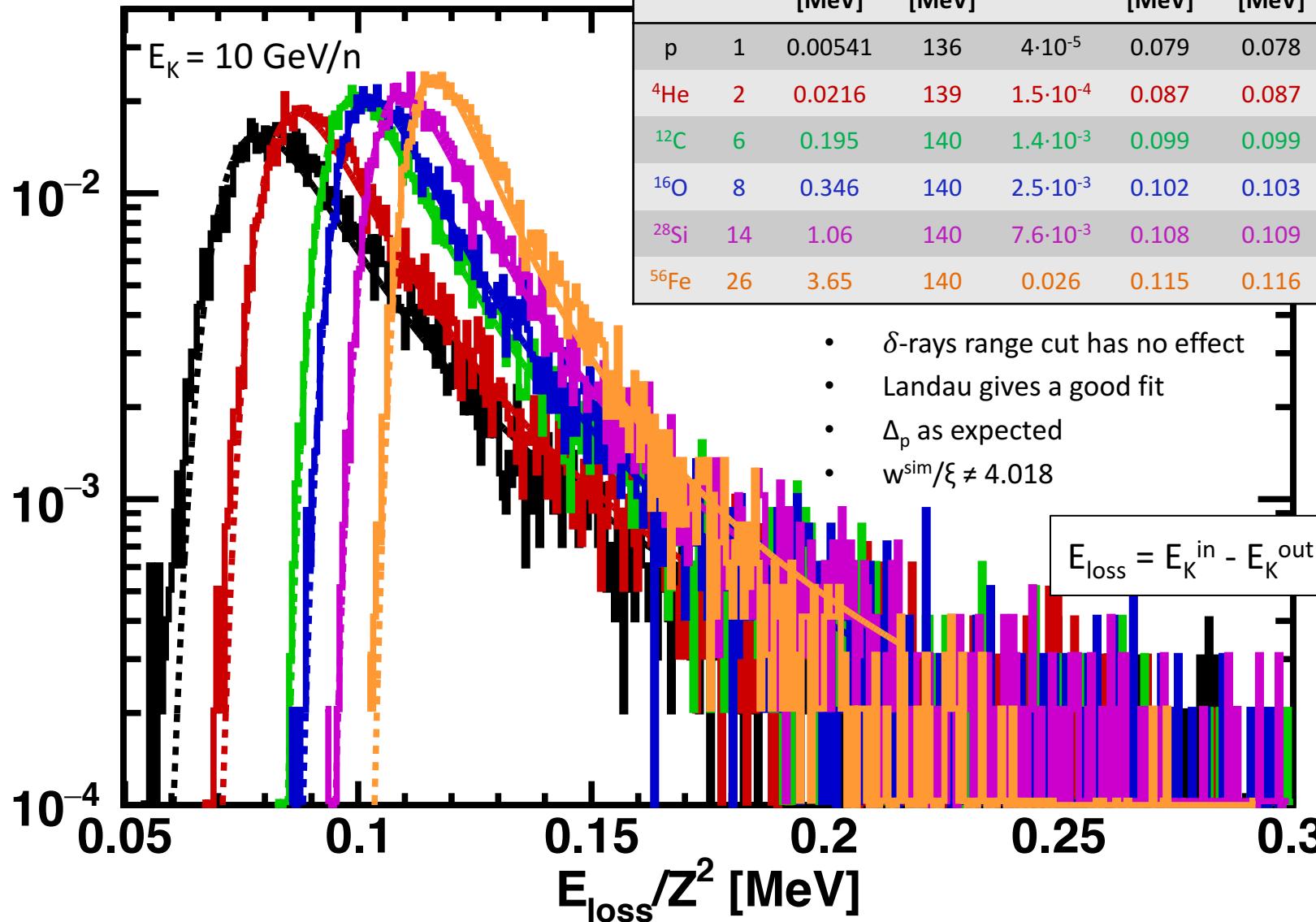
$$w_L \sim 4.018\xi$$

→ Verification with MC

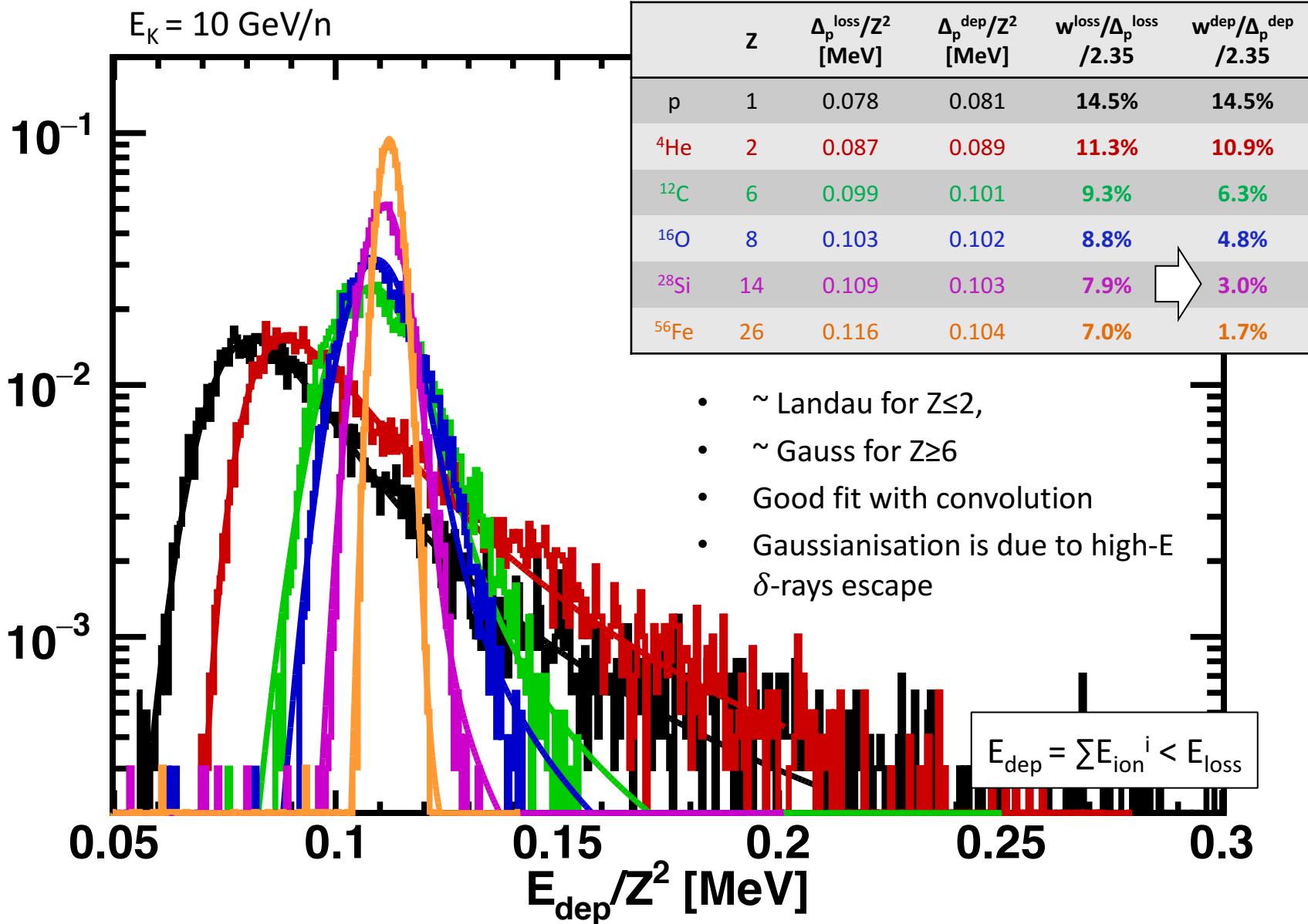


Energy Loss in 300 μm Silicon

From a simple GEANT4 simulation.

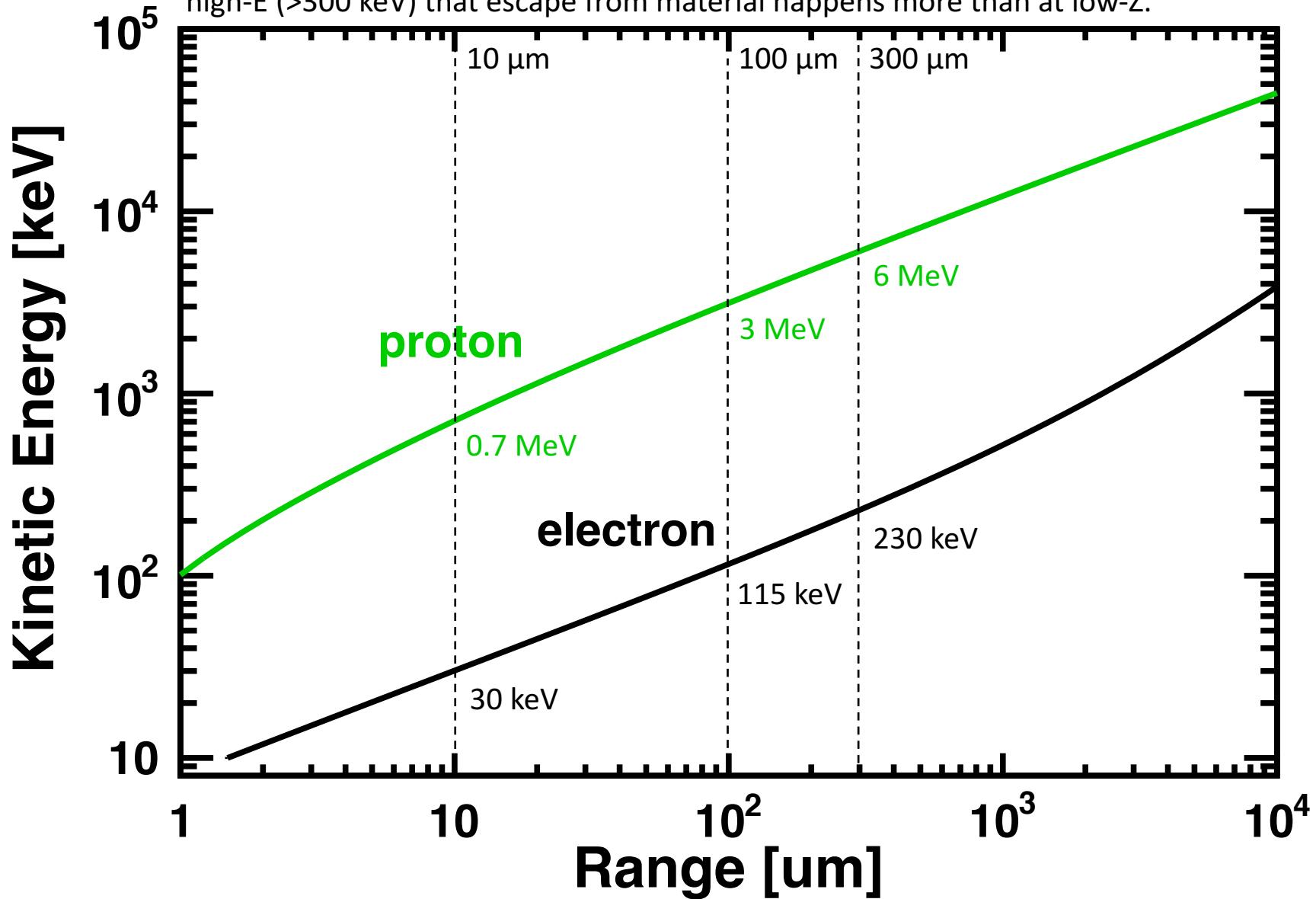


Energy Deposition in 300 μm Silicon



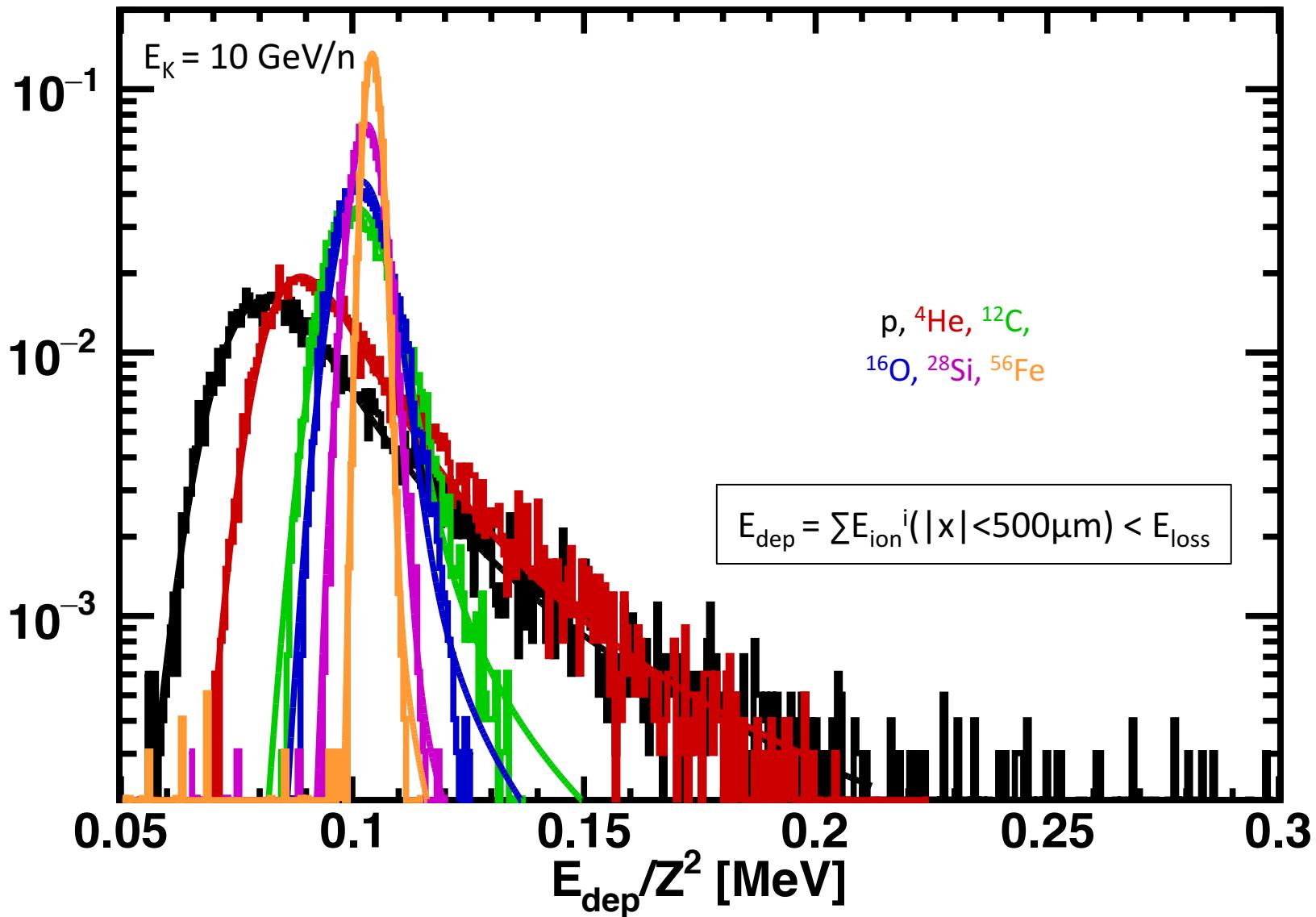
δ -Rays Escape

δ -rays production cross section $d\sigma/dE \approx kZ^2/E^2$. At high-Z emission of δ -rays of high-E (>300 keV) that escape from material happens more than at low-Z.



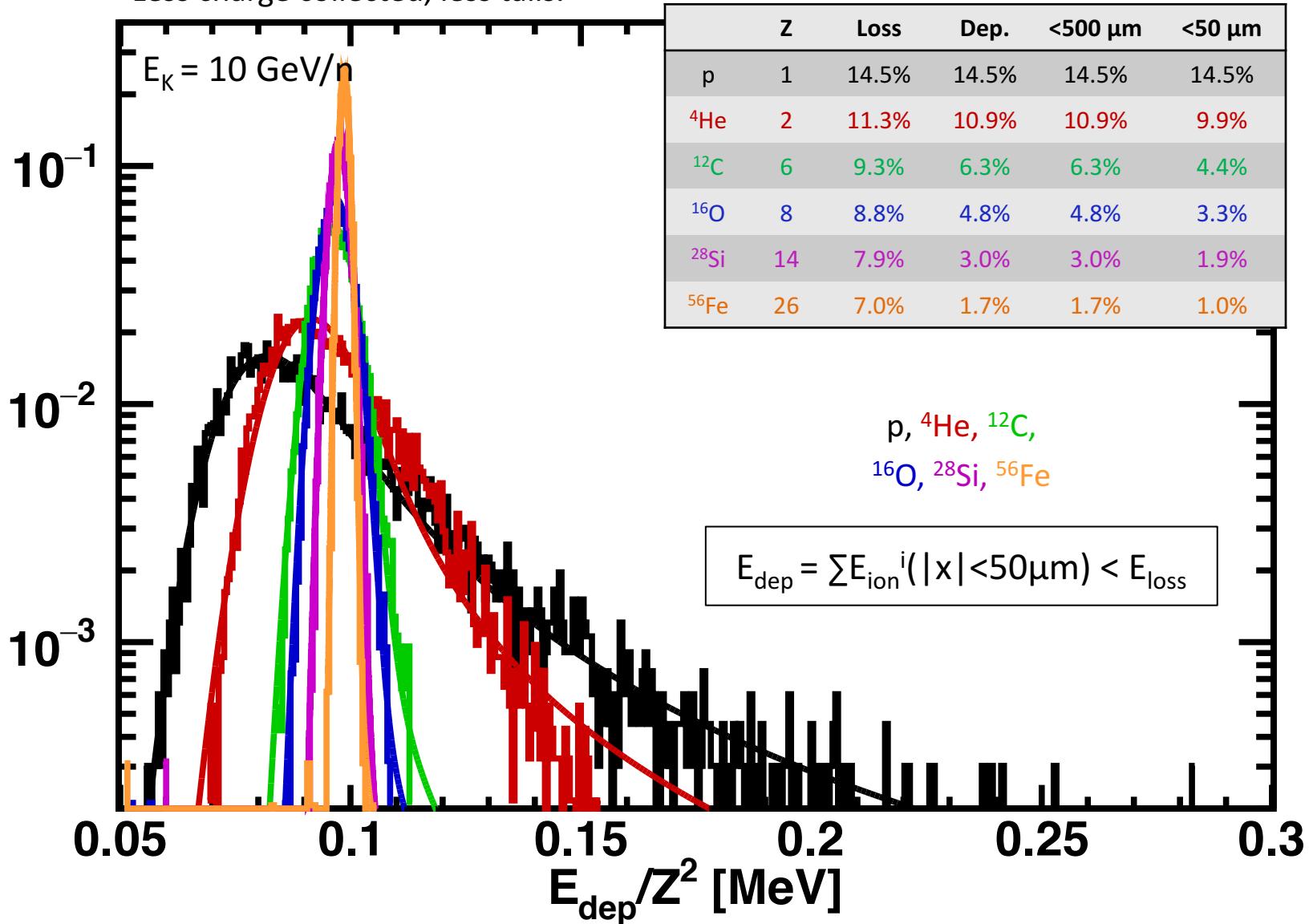
Energy Loss in 300 μm Silicon (“cluster”)

Pretty similar to previous.



Energy Loss in 300 μm Silicon (“strip”)

Less charge collected, less tails.



Charge Measurement and Resolution

$$E = k \frac{z^2}{\beta^2} f(\beta\gamma) = K z^2$$

$$\sigma_E = \frac{dE}{dz} \sigma_z = 2Kz\sigma_z$$

$$\frac{\sigma_z}{z} = \frac{1}{2} \frac{\sigma_E}{E}$$

$$\left(\frac{\sigma_E}{E} \right)_{\text{stra}} = \frac{1}{2.35} \frac{w_L}{\Delta p} \propto \frac{1}{\sqrt{z}}$$

Straggling
(from simulation)

$$\left(\frac{\sigma_E}{E} \right)_{\text{stat}} = \sqrt{\frac{WF}{E}} \propto \frac{1}{z}$$

E/W = number of carriers (W = 3.6 eV for Si)
F = Fano's factor (0.12 for Si)

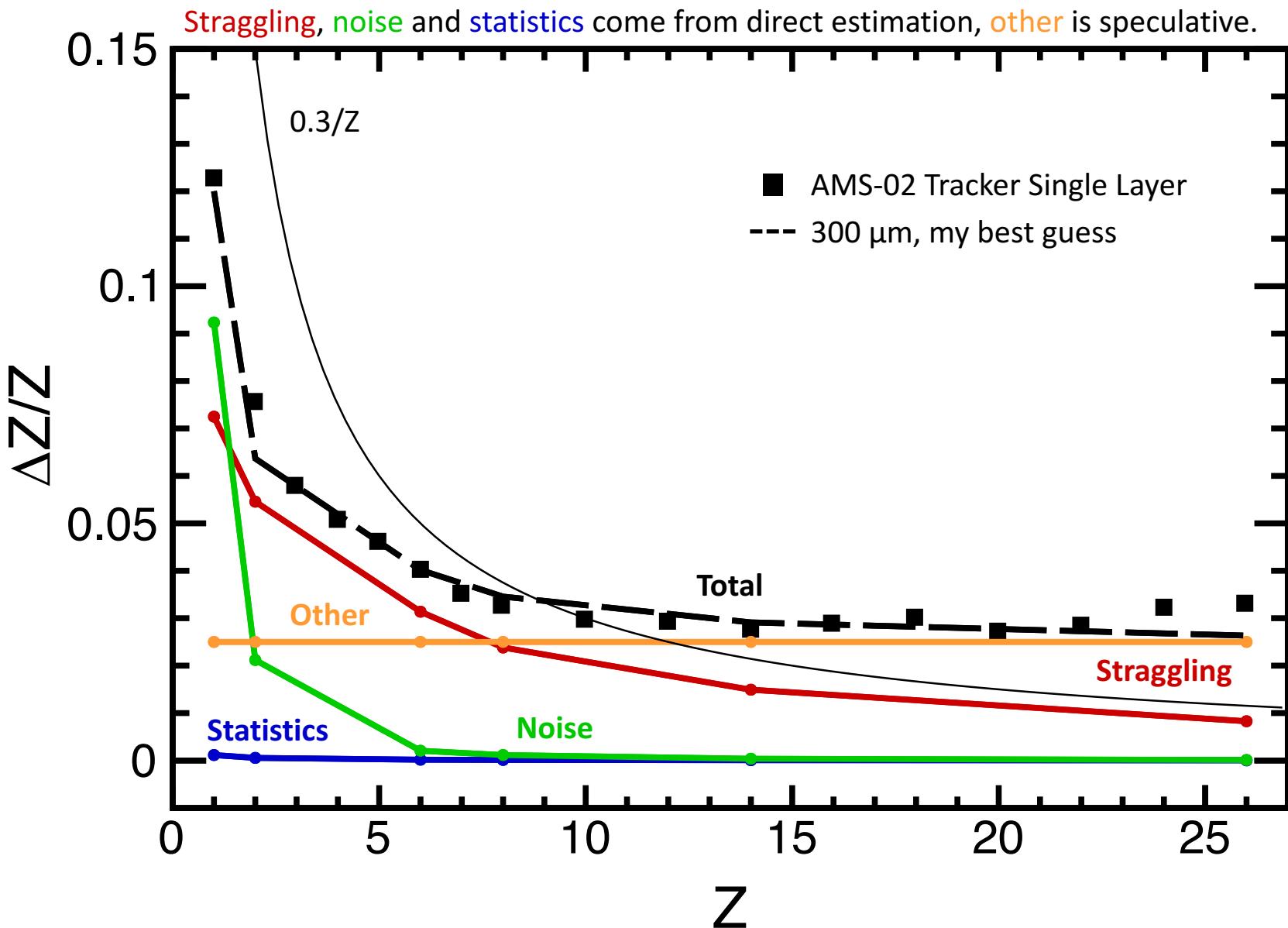
Statistical
(below % even with 50 μm)

$$\left(\frac{\sigma_E}{E} \right)_{\text{noise}} = \frac{c_{\text{noise}}}{E} \propto \frac{1}{z^2}$$

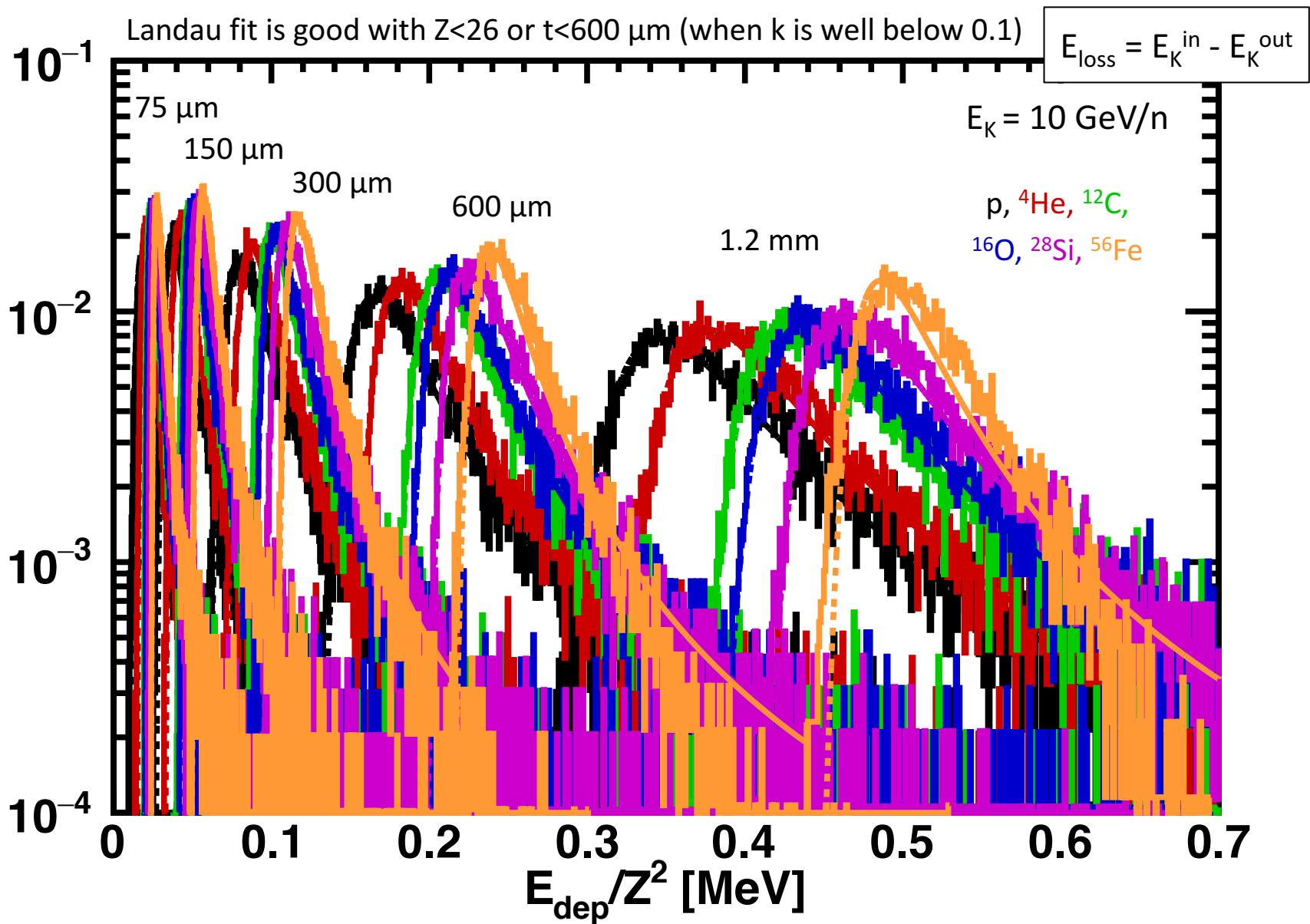
Noise
(depends on S/N)

Other: systematics due *detector effects*, that can be *irreducible* (saturation, space charge, sample-and-hold) or that can be *improved* with better understanding of the detector (amplification non-linearities, angular and spatial dependencies, ...). For the latter, large statistics at high-Z may help.

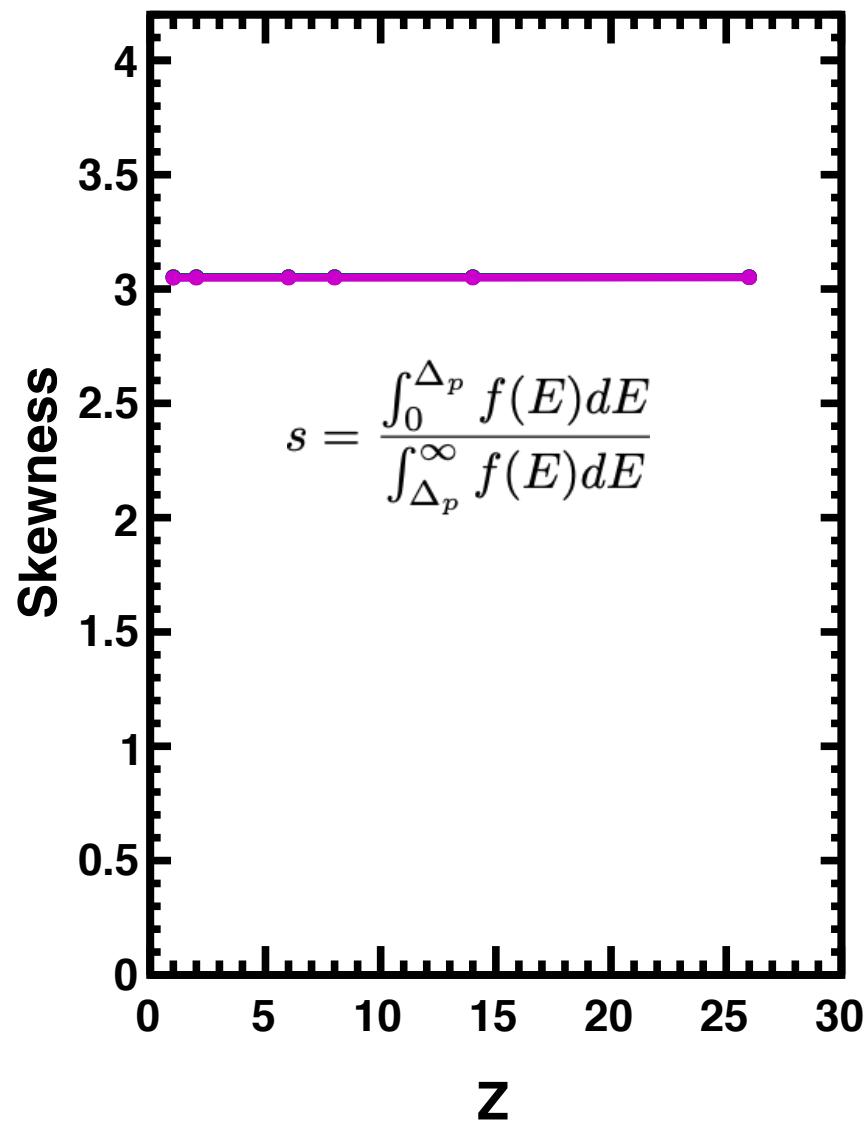
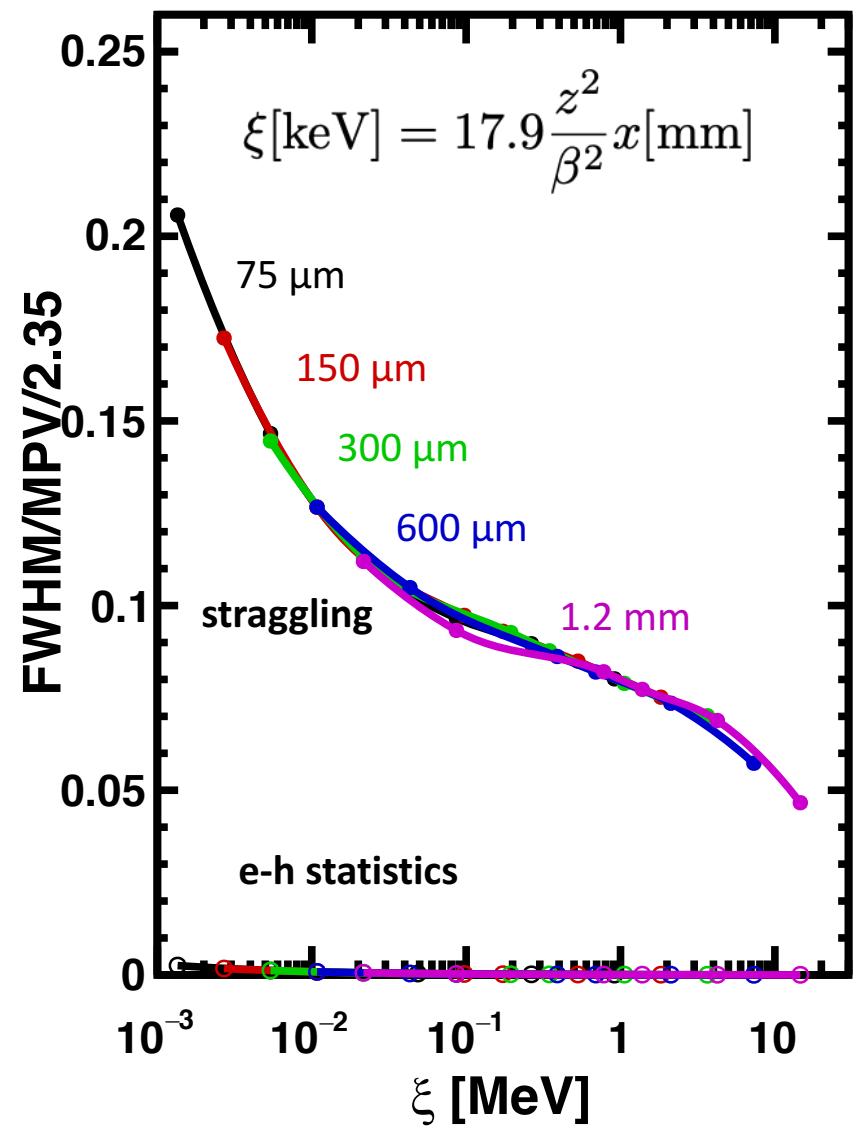
AMS-02 Single Layer Charge Resolution



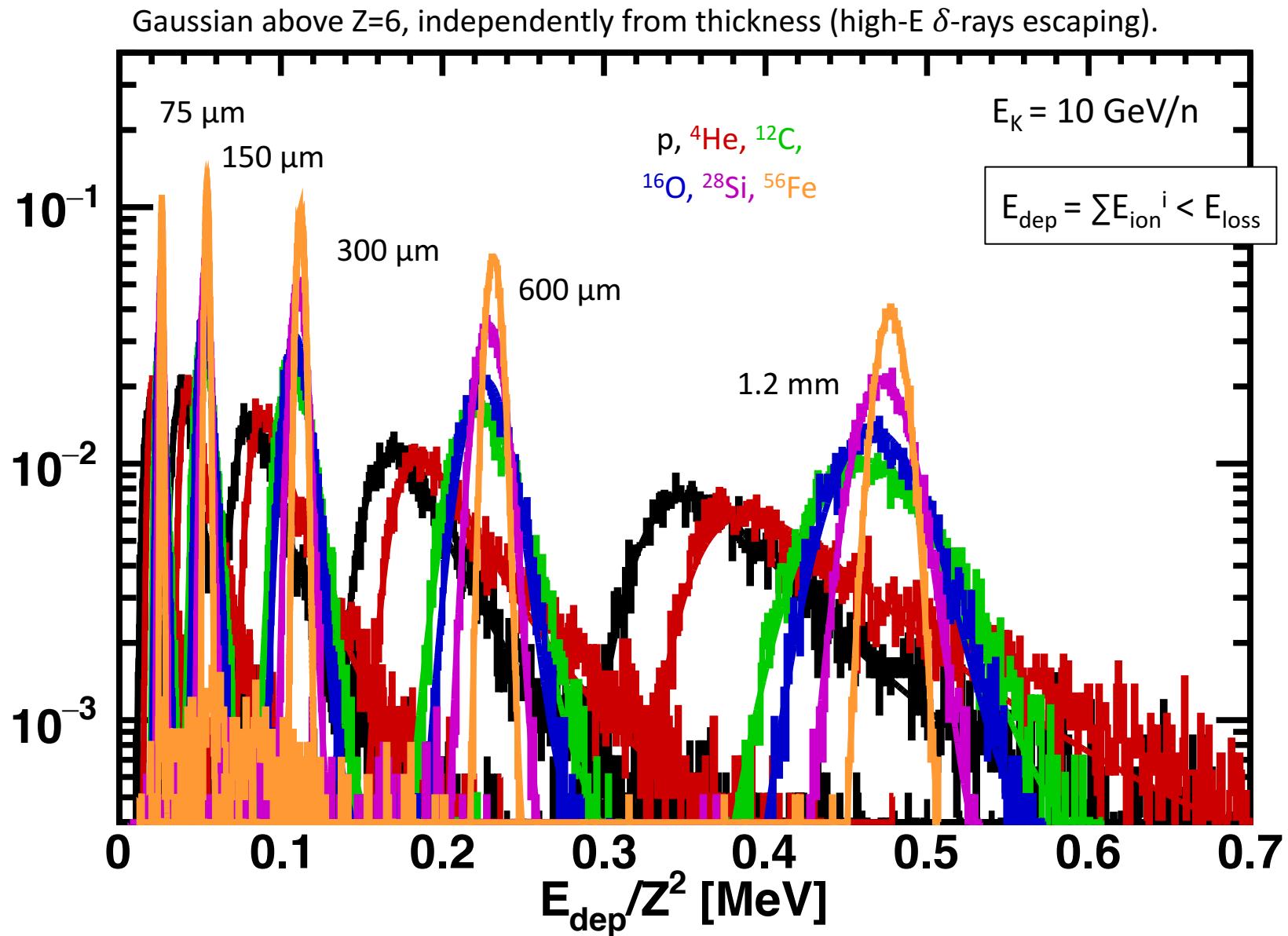
Single Layer Energy Loss for Different Thicknesses



Single Layer Energy Loss for Different Thicknesses

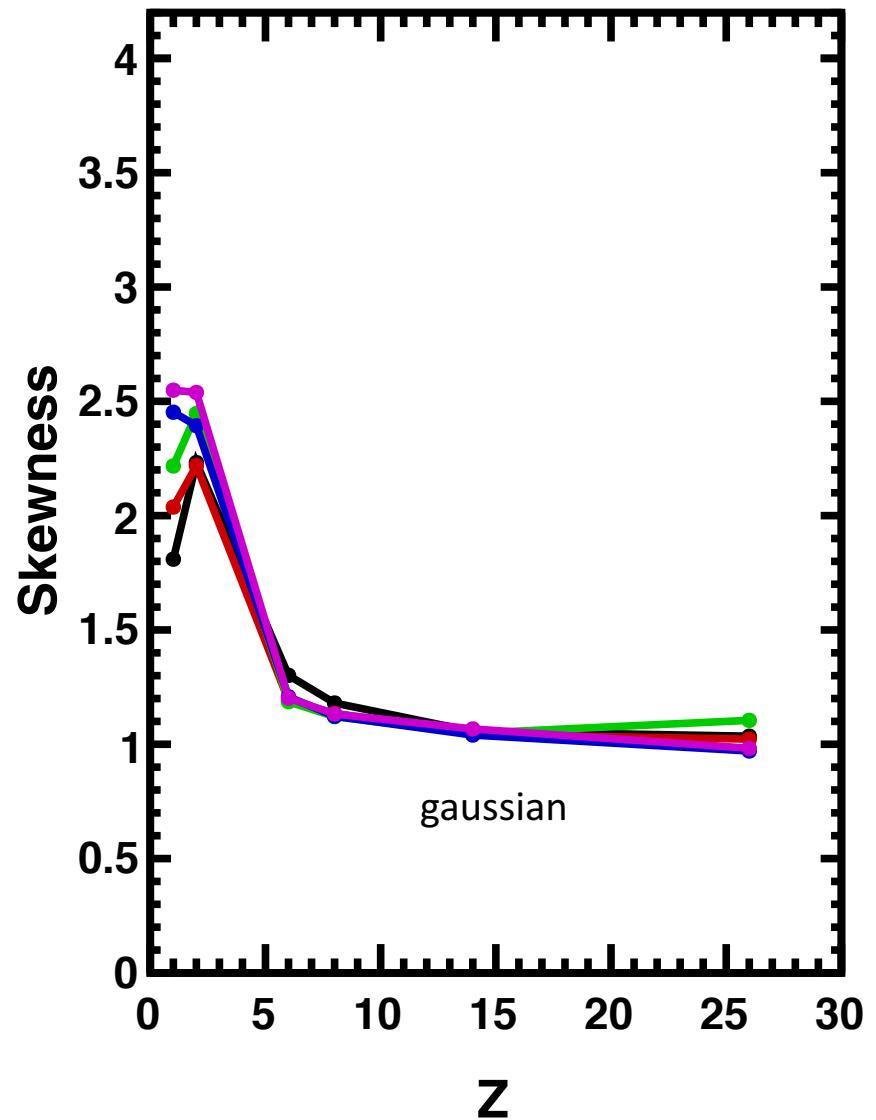
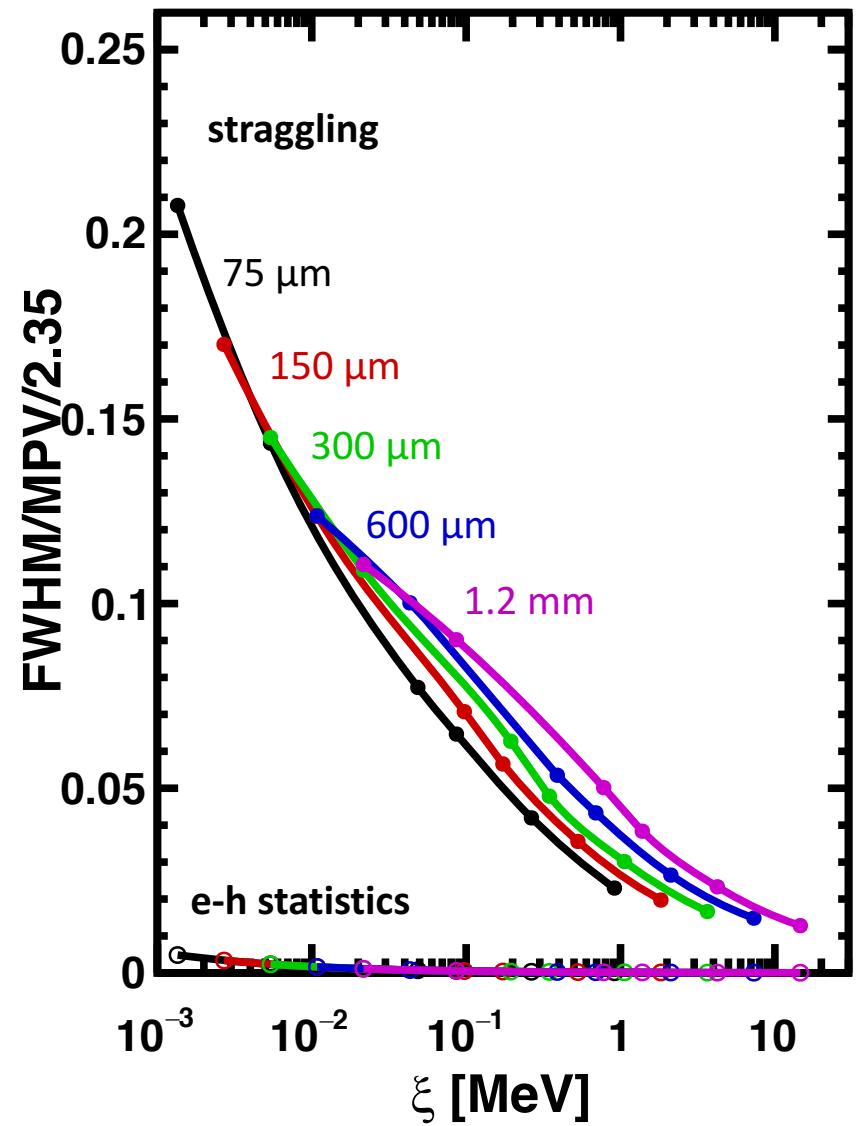


Single Layer Energy Deposit inside 500 μm for Different Thicknesses



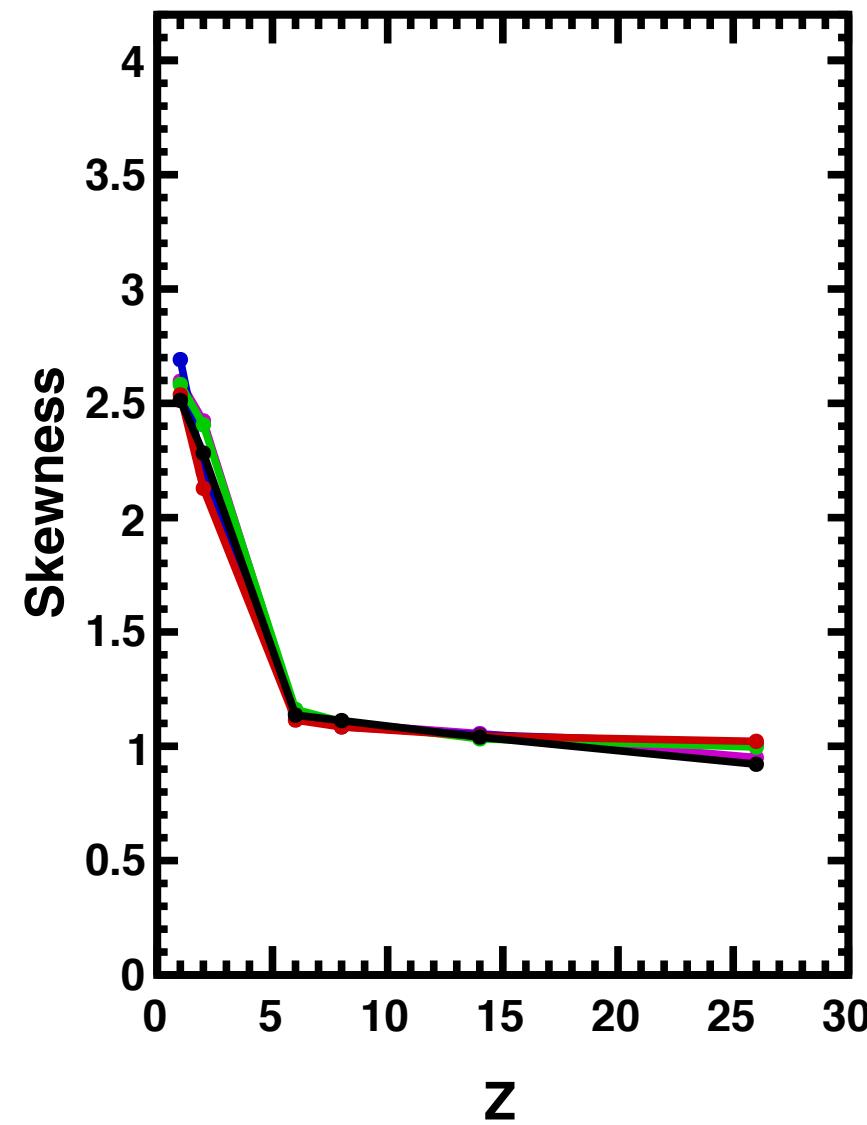
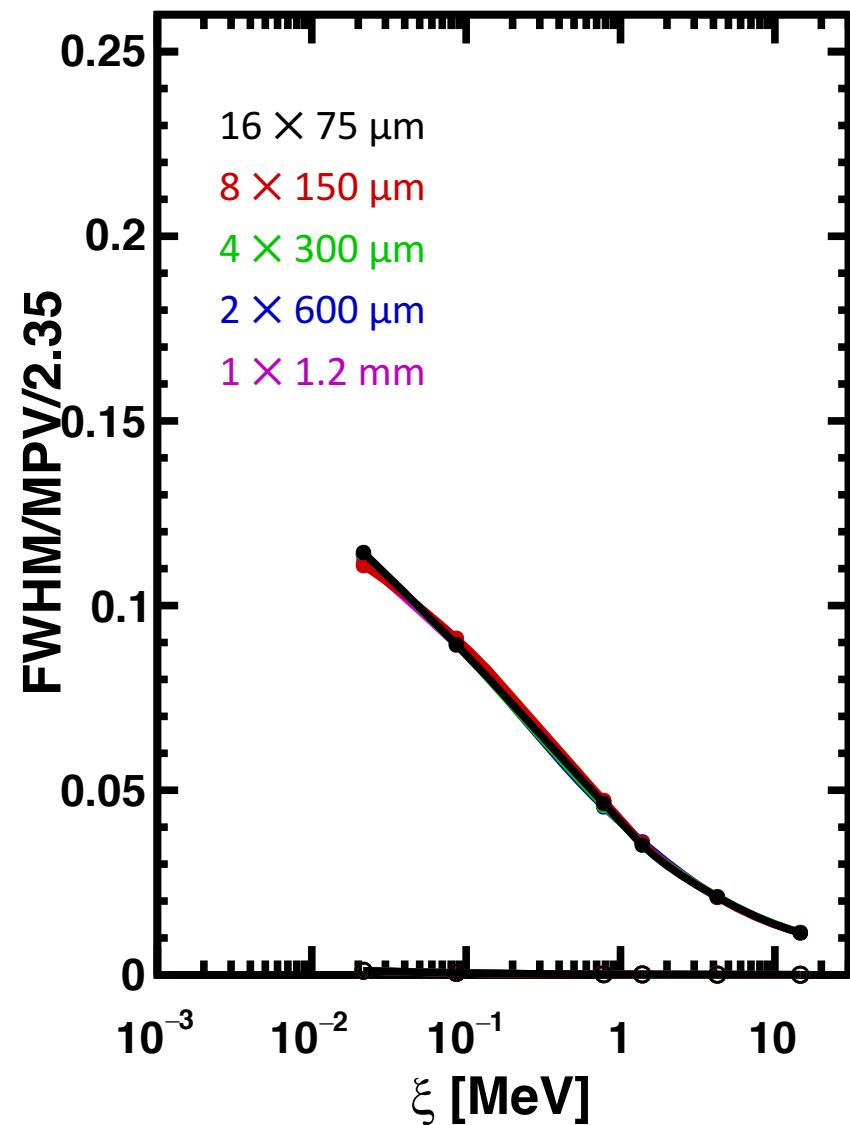
Single Layer Energy Deposit inside 500 μm for Different Thicknesses

Similar things can be seen for integral and <50 μm energy deposit.



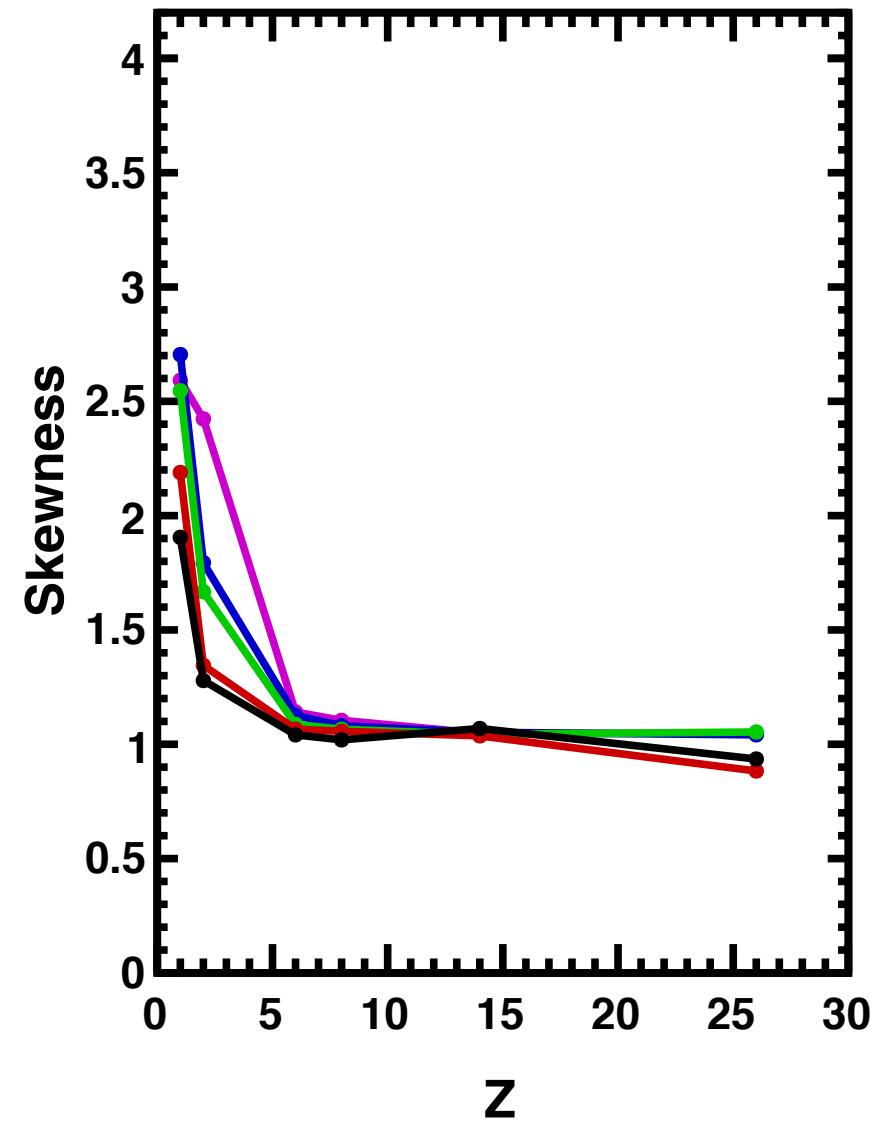
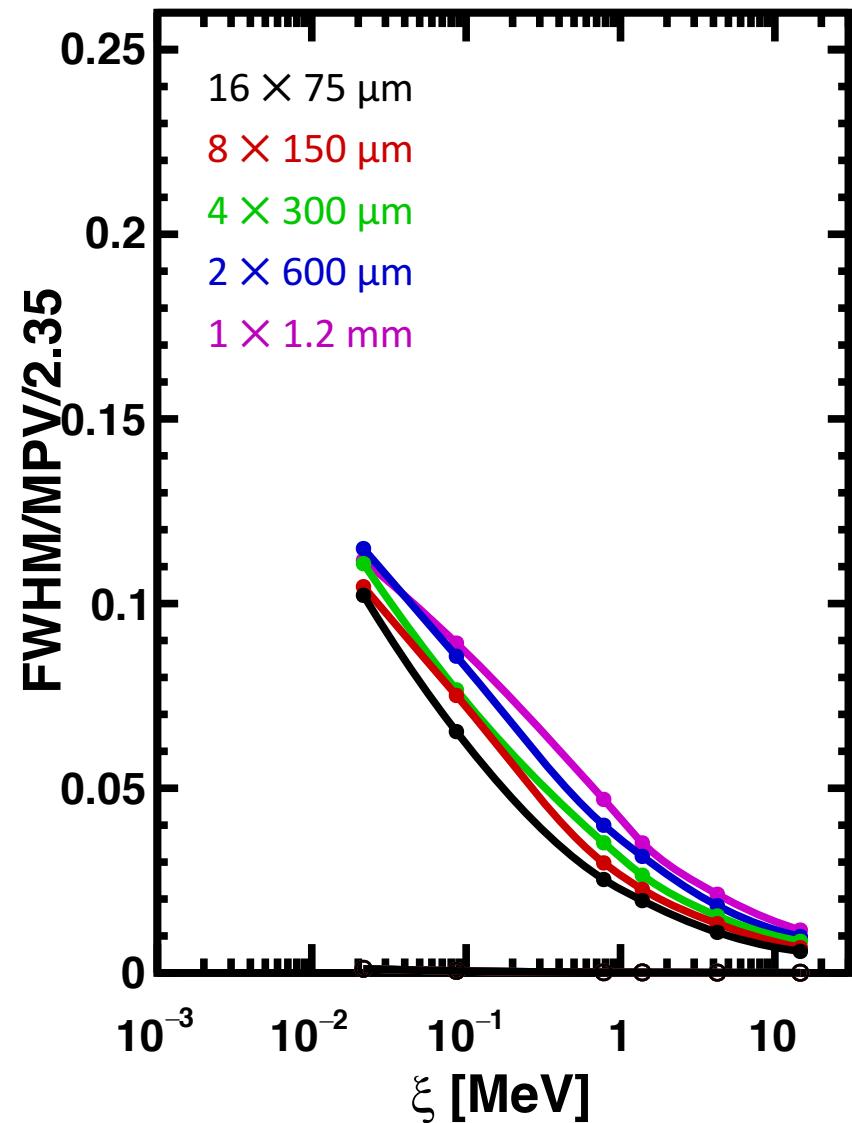
Energy Deposit inside 500 μm for the Same Overall Thickness of 1.2 mm

As expected, just by simple segmentation, there is no difference for any energy deposition/loss.



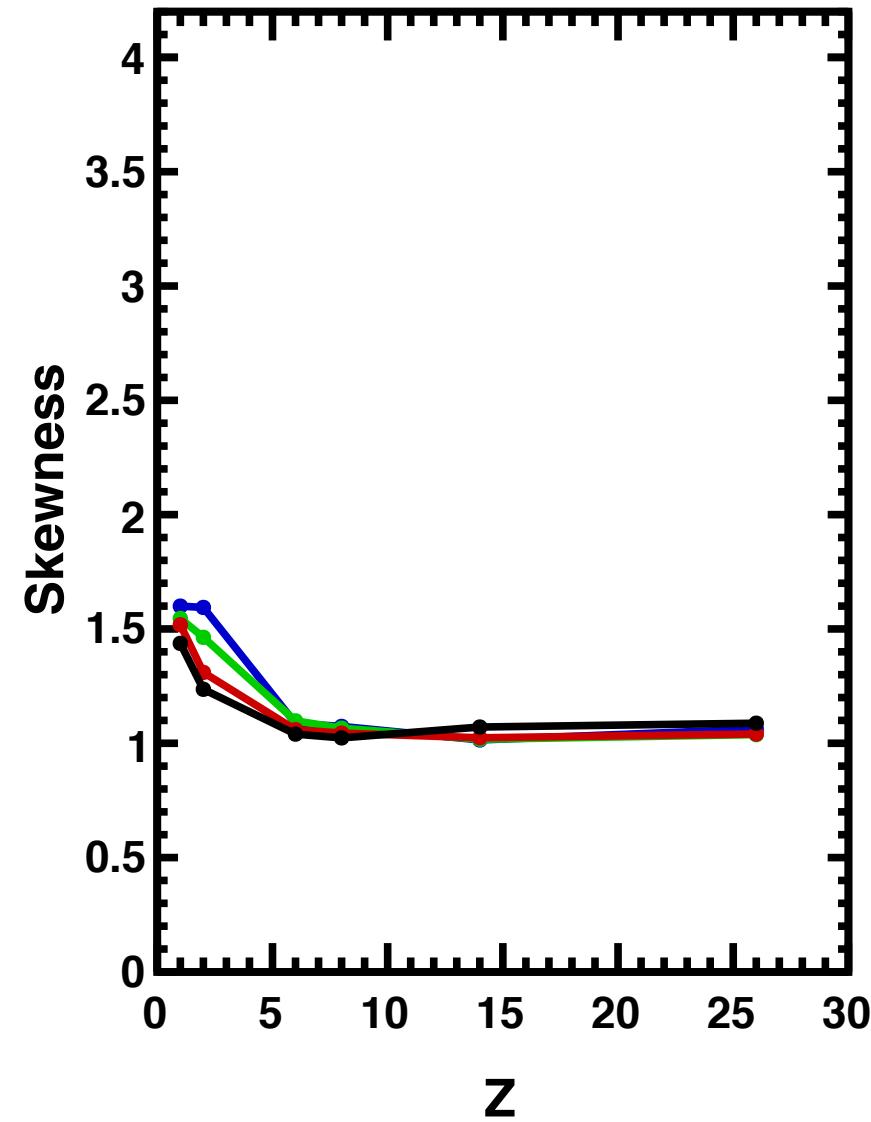
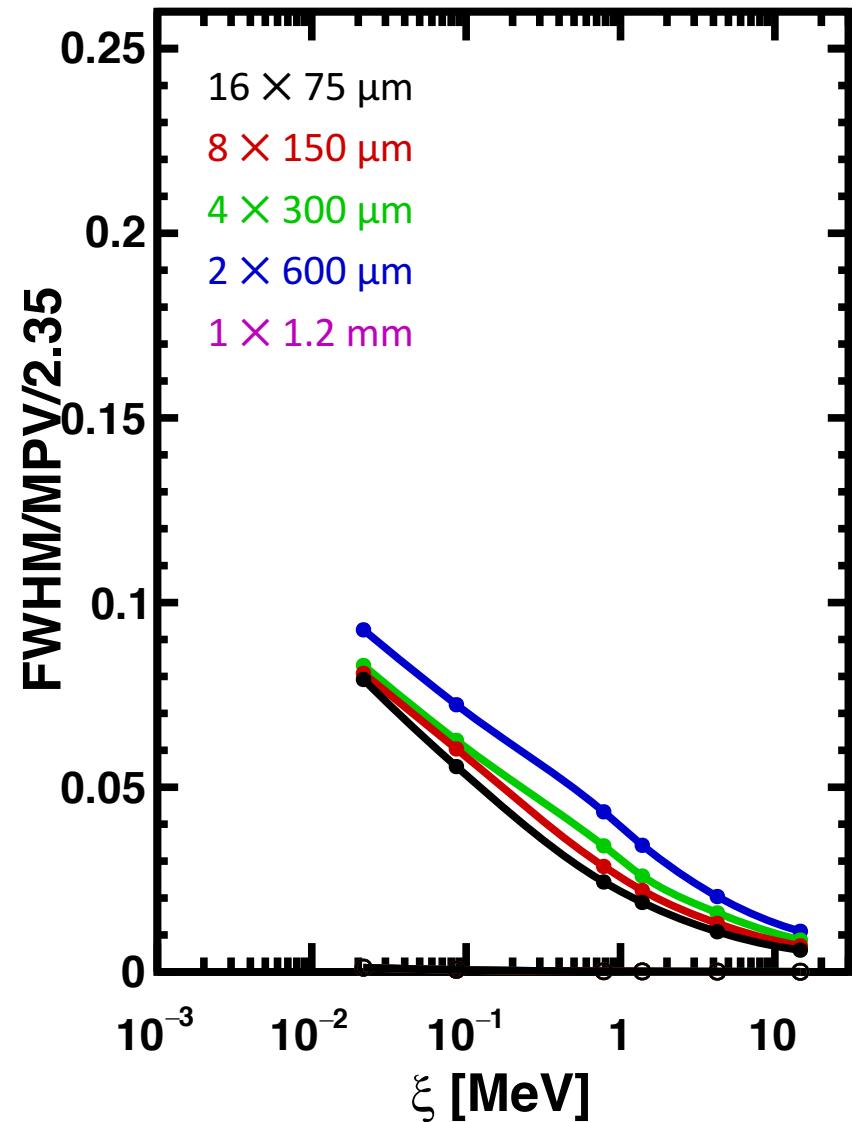
Energy Deposit inside 500 μm for the Same Overall Thickness of 1.2 mm

Some improvement arise if there is a gap, here of 1 cm (reduce δ -rays correlations).



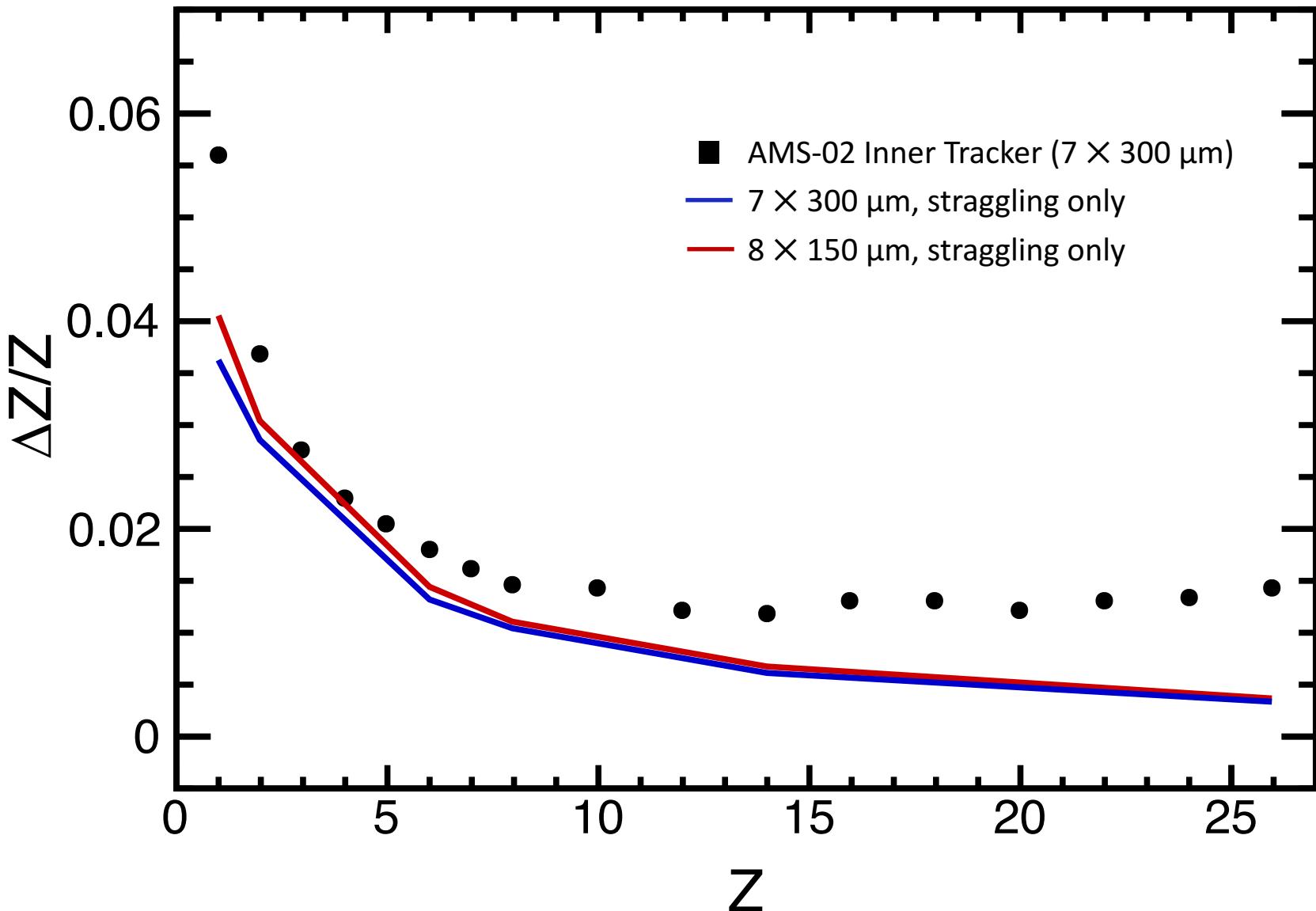
Energy Deposit inside 500 μm for the Same Overall Thickness of 1.2 mm

Additional improvement comes from the use of truncated mean (use of likelihood ...).



AMS-02 Inner Tracker Charge Resolution

Even if the use of $8 \times 150 \mu\text{m}$ has an intrinsic lower performance, it seems adequate.



Conclusions

A simple simulation able to give a baseline charge performance has been developed and verified with AMS-02 data.

At low-Z important contribution from straggling and noise.

At high-Z systematics could be dominant. It is important to plan ion beam test campaigns to check the linearity of the system and understand charge dependence from impact angle and coordinate. Also a uniformity of the response of the front-end electronics can be important for an accurate calibration.

A thin SCD with 8 layers of 150 μm has been studies and has an intrinsic resolution that is adequate (to be confirmed in test beam).

A more detailed performance evaluation of different scenarios will be carried out with HERD simulation.